

18-032

PREPARATION AND CHARACTERIZATION OF MOCVD THIN FILM CHROMIUM DIOXIDE COATINGS

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Chromium dioxide (Cr_2O_3) films have been widely used to increase the corrosion and wear resistance of metallic substrates. Many techniques have been used to deposit Cr_2O_3 films on a variety of substrates. This paper presents the preparation of Cr_2O_3 thin films using a custom made horizontal metal-organic chemical vapor deposition (MOCVD) apparatus at 600 °C with film growth pressure of 2 mbar. Chromium acetylacetonate was used as the chromium precursor and to select the temperature in nitrogen at which to use this precursor in the MOCVD apparatus, its mass loss as a function of temperature was determined with a thermobalance. The Cr_2O_3 films were characterized using scanning electron microscopy and x-ray diffraction analysis. The isothermal oxidation behavior of Cr_2O_3 film coated carbon steel at 600 °C in air was also determined using a thermogravimetric analyzer. The Cr_2O_3 thin film increased markedly the oxidation resistance of the steel.